

CS-108 Calibration Substrate Key

(all structures for probes with one ground)

Locatio	on #	Description	Coordinates (X,Y in micrometers)
00	open	pads (500 to 1250 micrometer pitch)	(0, 0) from 00
01	50 oh	m loads (500 to 1250 micrometer pitch)	(11500, 0) from 00
10	6600	micrometer 50 ohm coplanar line (50 to 250 micrometer pitch)	(175, 4155) from 41
20	shorti	ng bars (500 to 1250 micrometer pitch)	(0, 2025) from 00
21	550 n	nicrometer long 50 ohm line (500 to 1250 micrometer pitch)	(11500, 2025) from 00
30	right	angle open pads for G,S probes (pair) (50 to 250 micrometer pitch)	(0, 0) from 30
31		angle shorting bars for G,S probes (pair) (50 to 250 micrometer pitch)	(2700, 0) from 30
33		angle load for G,S probes (pair) (50 to 250 micrometer pitch)	(5400, 0) from 30
34	right	angle 50 ohm line for G,S probes (50 to 250 micrometer pitch)	(8100, 0) from 30
40	right	angle open pads for S,G probes (pair) (50 to 250 micrometer pitch)	(0, 0) from 40
41	350 n	nicrometer spacing alignment structure #1	(0, 0) from 41
42	right	angle shorting bars for S,G probes (pair) (50 to 250 micrometer pitch)	(2700, 0) from 40
43		nicrometer spacing alignment structure #2	(3400, 0) from 41
44	right	angle 50 ohm loads for S,G probes (pair) (50 to 250 micrometer pitch)	(5400, 0) from 40
45	right	angle 50 ohm line for S,G probes (pair) (50 to 250 micrometer pitch)	(8100, 0) from 40
50	open	pads for non mirror image probes (pair) (50 to 250 micrometer pitch)	(-1725, 2000) from 41
51	open	pads (pair) (50 to 250 micrometer pitch)	(0, 2000) from 41
52	open	pads (pair) (50 to 250 micrometer pitch)	(1700, 2000) from 41
53	open	pads (pair) (50 to 250 micrometer pitch)	(3400, 2000) from 41
54		pads (pair) (50 to 250 micrometer pitch)	(5100, 2000) from 41
55	open	pads (pair) (50 to 250 micrometer pitch)	(6800, 2000) from 41
56	open	pads (pair) (50 to 250 micrometer pitch)	(8500, 2000) from 41
60	shorti	ng bar for non mirror image probes (pair) (50 to 250 micrometer pitch)	(-1750, 4000) from 41
61	shorti	ng bar (pair) (50 to 250 micrometer pitch)	(0, 4000) from 41
62	shorti	ng bar (pair) (50 to 250 micrometer pitch)	(1700, 4000) from 41
63	shorti	ng bar (pair) (50 to 250 micrometer pitch)	(3400, 4000) from 41
64	shorti	ng bar (pair) (50 to 250 micrometer pitch)	(5100, 4000) from 41
65	shorti	ng bar (pair) (50 to 250 micrometer pitch)	(6800, 4000) from 41
66	shorti	ng bar (pair) (50 to 250 micrometer pitch)	(8500, 4000) from 41
70	50 oh	m loads for non mirror image probes (pair) (75 to 250 micrometer pitch)	(-1750, 6000) from 41
71	50 oh	m loads (pair) (50 to 250 micrometer pitch)	(0, 6000) from 41
72	50 oh	m loads (pair) (50 to 250 micrometer pitch)	(1700, 6000) from 41
73	50 oh	m loads (pair) (50 to 250 micrometer pitch)	(3400, 6000) from 41
74	50 oh	m loads (pair) (50 to 250 micrometer pitch)	(5100, 6000) from 41
75	50 oh	m loads (pair) (50 to 250 micrometer pitch)	(6800, 6000) from 41
76	50 oh	m loads (pair) (50 to 250 micrometer pitch)	(8500, 6000) from 41
80	50 oh	m coplanar line for non mirror image probes (50 to 250 micrometer pitch)	(-1725, 8000) from 41
81	400 n	nicrometer long single sided line (50 to 250 micrometer pitch)	(0, 8000) from 41
82	400 n	nicrometer long single sided line (50 to 250 micrometer pitch)	(1700, 8000) from 41
83	400 n	nicrometer long single sided line (50 to 250 micrometer pitch)	(3400, 8000) from 41
84	400 n	nicrometer long single sided line (50 to 250 micrometer pitch)	(5100, 8000) from 41
85		nicrometer long single sided line (50 to 250 micrometer pitch)	(6800, 8000) from 41
86		nicrometer long single sided line (50 to 250 micrometer pitch)	(8500, 8000) from 41
90		ng bars (250 to 500 micrometer pitch)	(0, -1500) from 110
91		nicrometer long 50 ohm coplanar line (250 to 500 micrometer pitch)	(11500, -1500) from 110
100		micrometer single sided line (50 to 800 micrometer pitch)	(175, 10914) from 41
110		pads (250 to 500 micrometer pitch)	(0, 0) from 110
111		m loads (250 to 500 micrometer pitch)	(11500, 0) from 110